

# Cleaning recipes in Oxford metal-RIE

Etch recipes	Main etch gases	Cleaning recipe
OPT - SiN <sub>x</sub> Etch OPT - SiO <sub>2</sub> Etch OPT - Cr Etch (ICP and RIE modes) OPT - TiO <sub>2</sub> Etch OPT - Nb Etch (ICP and RIE modes) OPT - W Etch	SF <sub>6</sub> , C <sub>4</sub> F <sub>8</sub> , CF <sub>4</sub> , CHF <sub>3</sub>	OPT - CLEAN O2/SF6
OPT - ZnO Etch OPT - ITO Etch (ICP and RIE modes) OPT - InP Etch	CH <sub>4</sub> , H <sub>2</sub>	OPT - CLEAN O2/SF6
OPT - Al Etch (ICP and RIE modes)	BCl <sub>3</sub>	OPT - CLEAN SF6+O2/SF6
OPT - GaAs via etch OPT - AlGaAs/GaAs Etch	Cl <sub>2</sub>	OPT - CLEAN Cl2/SF6